

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Date January 30, 2008

In re the Application of

Tsuyoshi NISHIZAWA

Group Art Unit: 1722

Application No.: 10/561,957

Examiner: S. MALEKZADEH

Filed: December 22, 2005

Docket No.: 126273

For: METHOD FOR PRODUCING SILICON EPITAXIAL WAFER AND SILICON EPITAXIAL
WAFER

**LARGE ENTITY PETITION FOR 1st - 3rd EXTENSION
OF TIME UNDER 37 C.F.R. §1.136(a) AND
TRANSMITTAL OF FEE UNDER 37 C.F.R. §1.17**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Transmitted herewith is a response to the outstanding Official Action in the above-identified patent application. The shortened statutory period having expired December 27, 2007, an extension of time for a period of two months is hereby requested.

The fees associated with this filing under 37 C.F.R. §1.136(a) are being paid electronically with this filing. The Commissioner is hereby authorized to charge any additional fee (or credit any overpayment) associated with this communication to Deposit Account No. 15-0461.

Respectfully submitted,



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**DEPOSIT ACCOUNT USE
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